

## Design, Fabrication and Test of MEMS Propulsion with Solid Propellant

*4th Round Table on Micro/Nano Technologies for Space*  
Presentation, May 21, 2003

Prof. You Zheng, Zhang Gaofei,  
Li Han, Wang Ziyang  
Dr. Ren Dahai, Gao Peng

Tsinghua Space Center  
Dept of Precision Instruments and Mechanology  
Tsinghua University, Beijing, P.R. China

Prof. Li Baoxuan, Dr. Hu Songqi

College of Astronautics  
Northwestern Polytechnical University  
Xi'an, P.R. China

## Outline

- **Micro Propulsion System Overview**
- **Structure Design**
- **Fabrication**
- **Propellant Research and Casting**
- **Modeling and Analysis**
- **Thruster Performance Prediction**

## Future Space System Require Micro Propulsion System

### ■ Future Space System and Requirement

- New Space System: Microspacecraft constellation, Formation Flying
- Requirement for Propulsion Subsystem: Low mass, accurate impulse bit, integration, facility

### ■ Several Micro Propulsion Implementation

- Gas Thruster
- Chemical Thruster: Solid propellant, Bi-propellant
- EP: FEEP, PPT's ( $\mu$  PPT), Colloid Thruster

# MICROPROPULSION

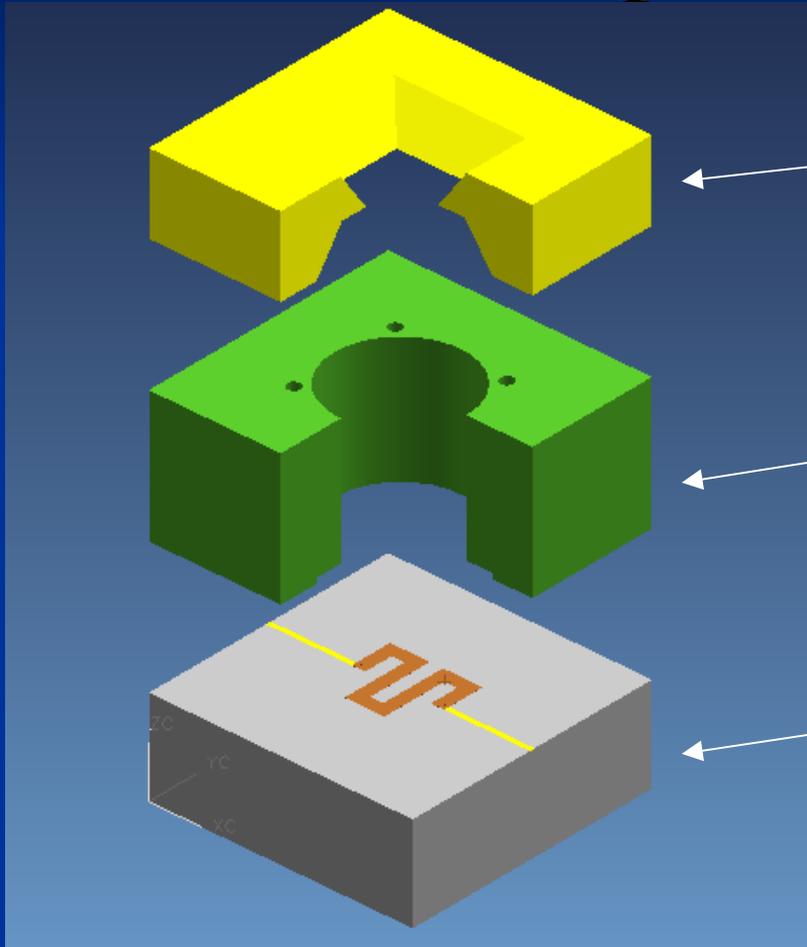
## Several Micro Propulsion System

<b>Propulsion System Type</b>	Gas Thruster (Snap-1)	PPT's (DAWGST AR PPT, AFRL $\mu$ PPT)	FEEP (Cesium)	MEMS (Chemical)	MEMS (Electrical, Especially colloid)
<b>Thruster Operation</b>	Continuous	Pulsed	Continuous	Pulsed	Pulsed
<b>Thrust Range</b>	45mN@0° C, 120mN@40° C	10~1e3 $\mu$ N	0.1~1200 $\mu$ N	1~1e5 $\mu$ N	>1e5 $\mu$ N
<b>Specific Impulse</b>	>60s	500~1500s	7000~11000 s	100~300	1000~2000s

## Advantages of MEMS Propulsion with Solid Propellant

- **Small:** Mass, volume are Small enough
- **Integration:** Integrated all parts in one chip
- **Adjustable Thrust:** The thrust force of each unit generated may be set by geometrical and dimensional considerations of the nozzle and chamber .
- **Addressable:** Several different units ignited together can generate various thrust force.
- **Reliability:** no moving parts

## Structure of MEMS Propulsion Unit



Top Layer-convergence and divergency nozzle on top

Middle Layer-combustion chamber with four exhaust holes

Bottom Layer-Pt resistor as ignitor

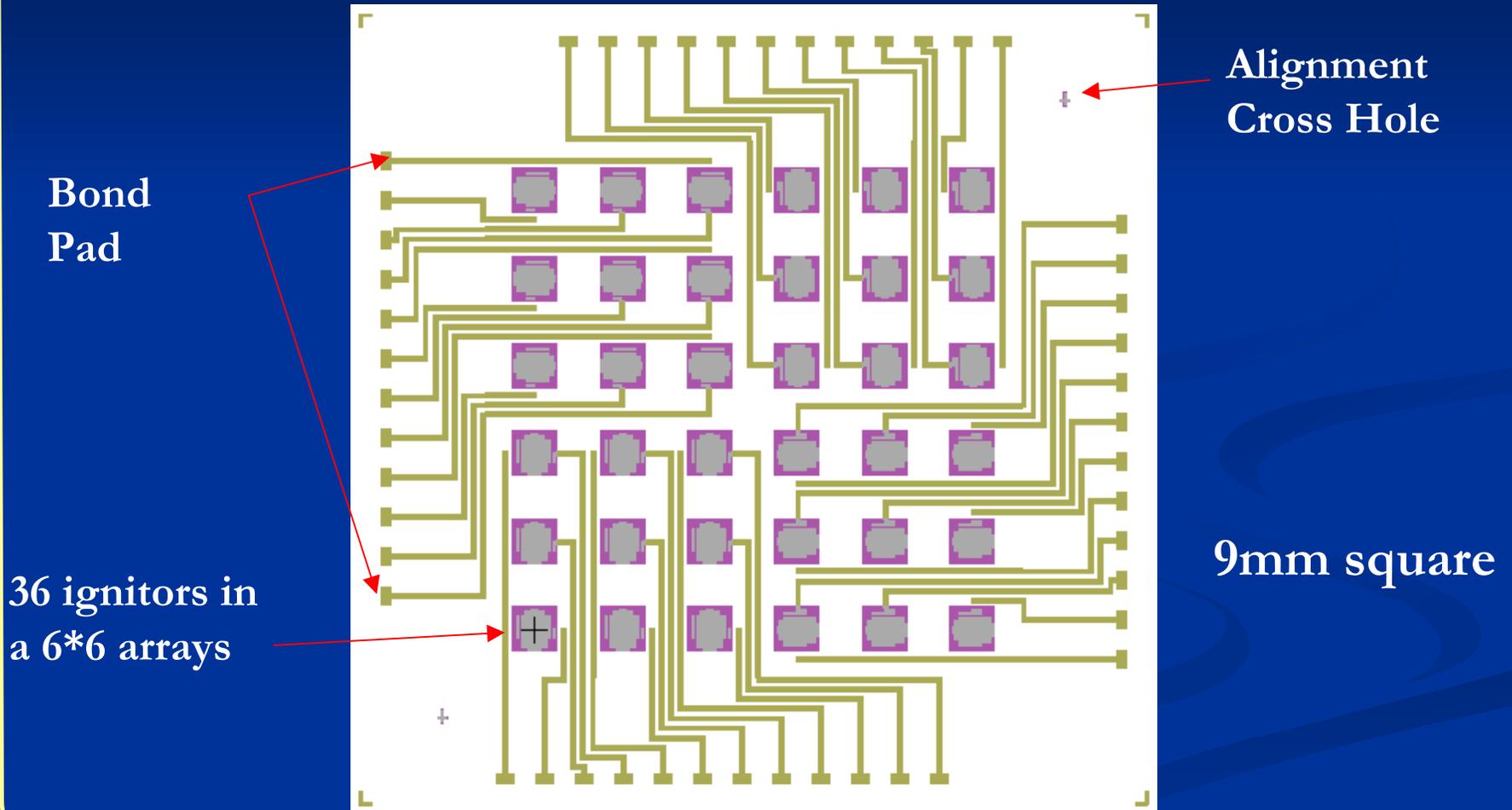
**Exploded View**

## Fabrication Process of Prototype

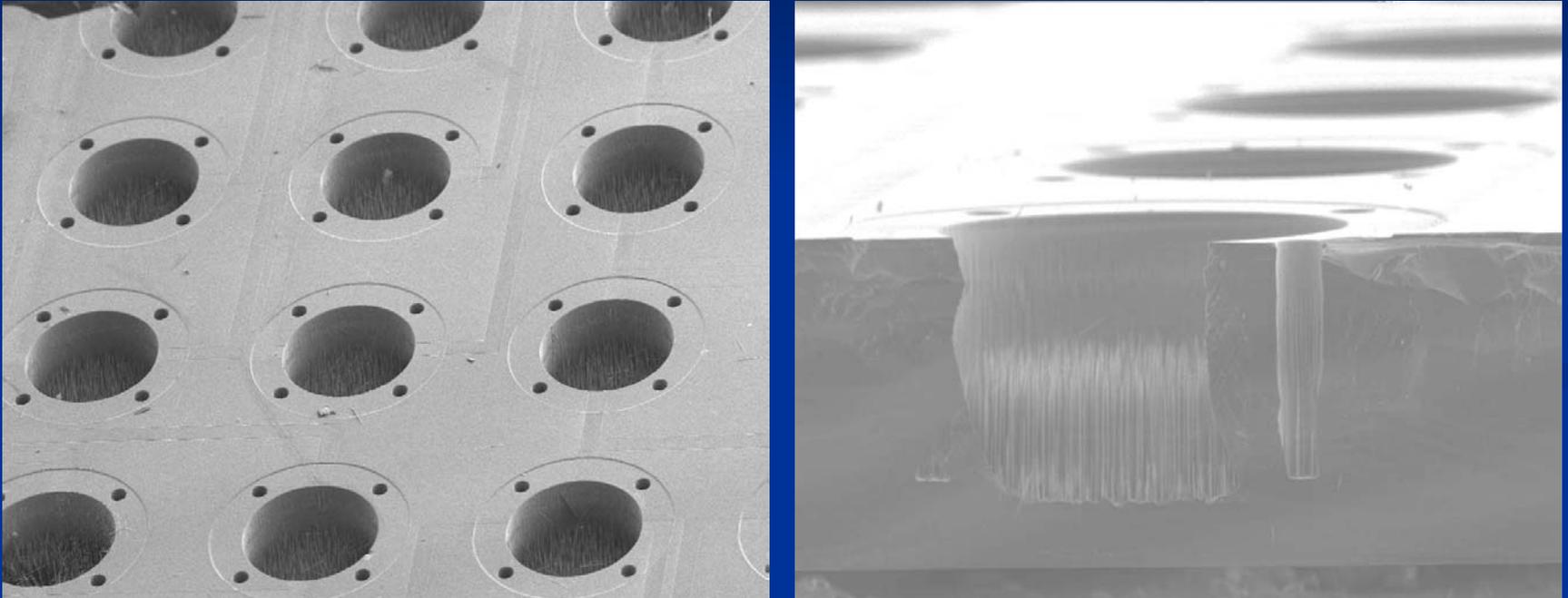
- Bottom Layer, Ignitor-Deposit Pt & Au orderly on the Prex7740, Pattern to realize the ignitor resistor, the electrical pads and the electrical supply lines.
- Middle Layer-ICP etch P-type (100) wafer to form the combustion chamber.
- Top Layer-KOH etch (100) wafer on both side to form the nozzle.

# MICROPROPULSION

## Top View of Bottom Layer

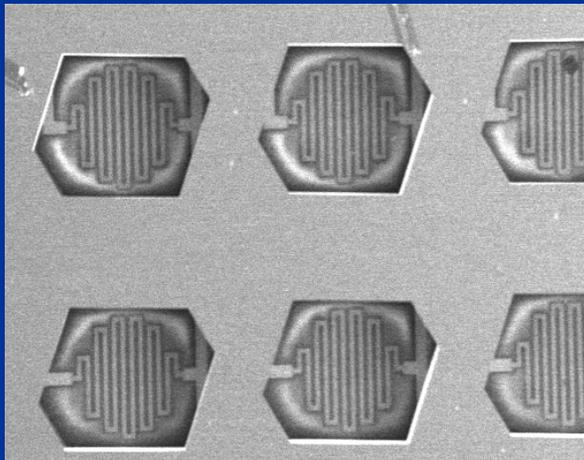
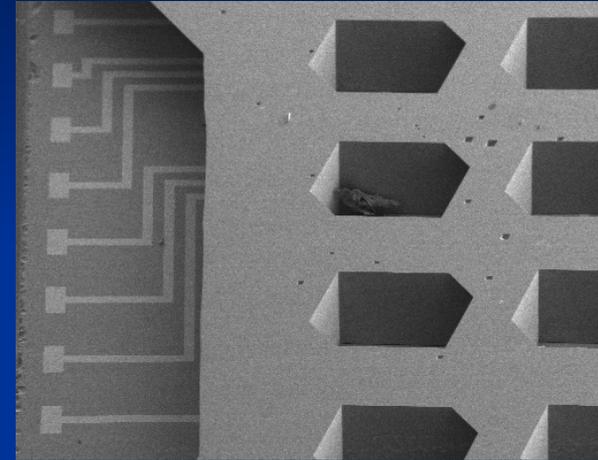
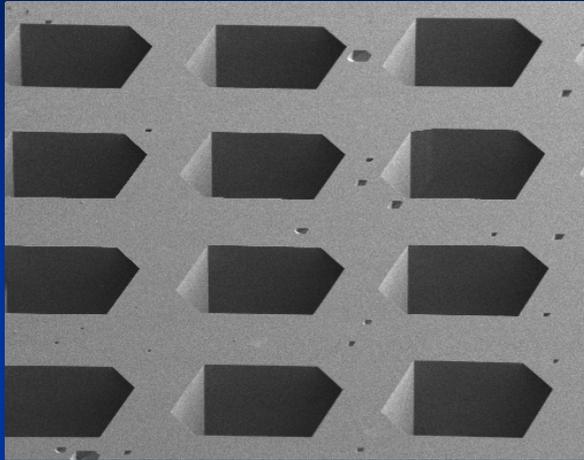


## SEM of The Thruster Structure



SEM (Scanning electron microscope) of  
ICP (Inductively Coupled Plasma) Etching  
Chamber with Four Exhaust Holes

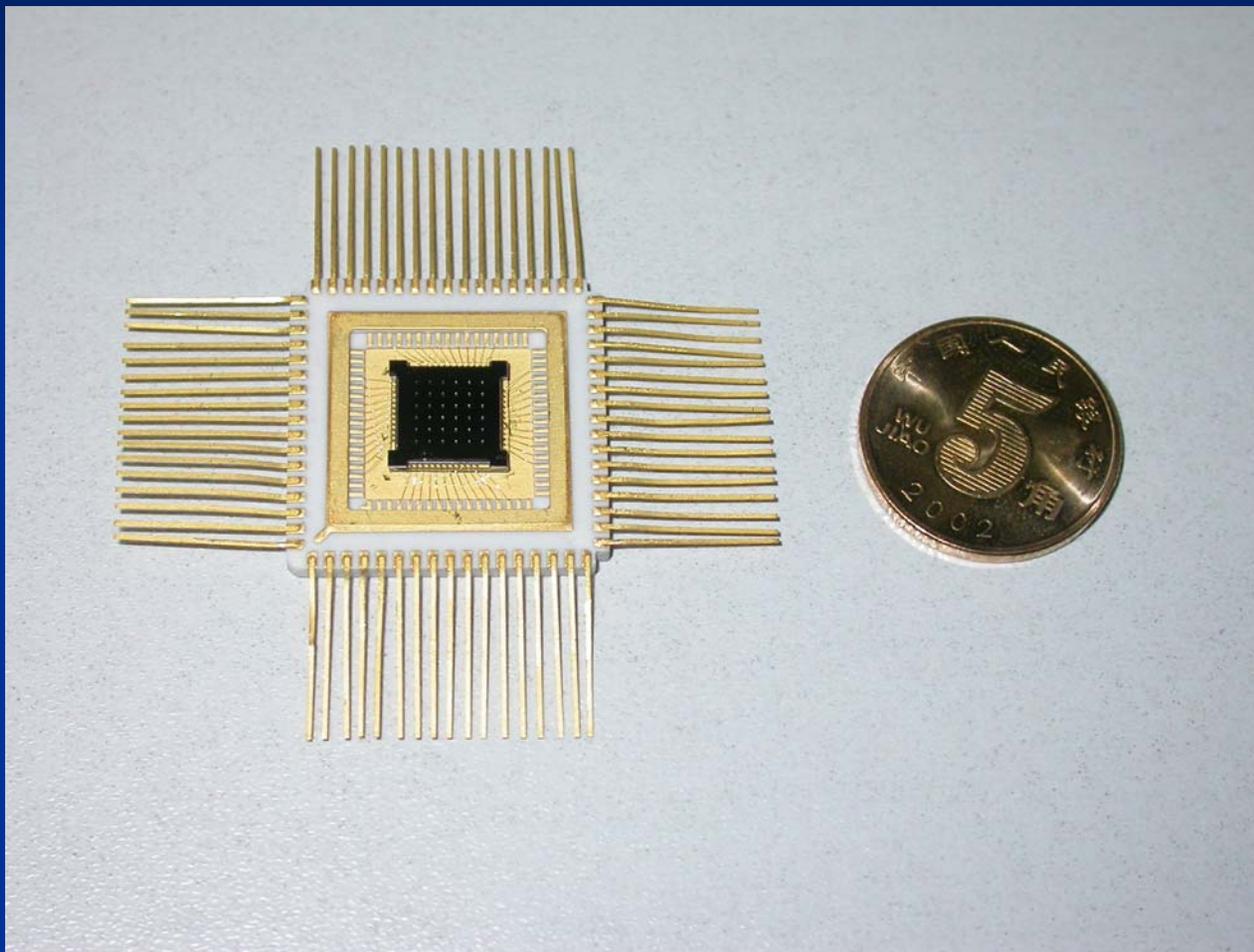
## SEM of The Thruster Structure



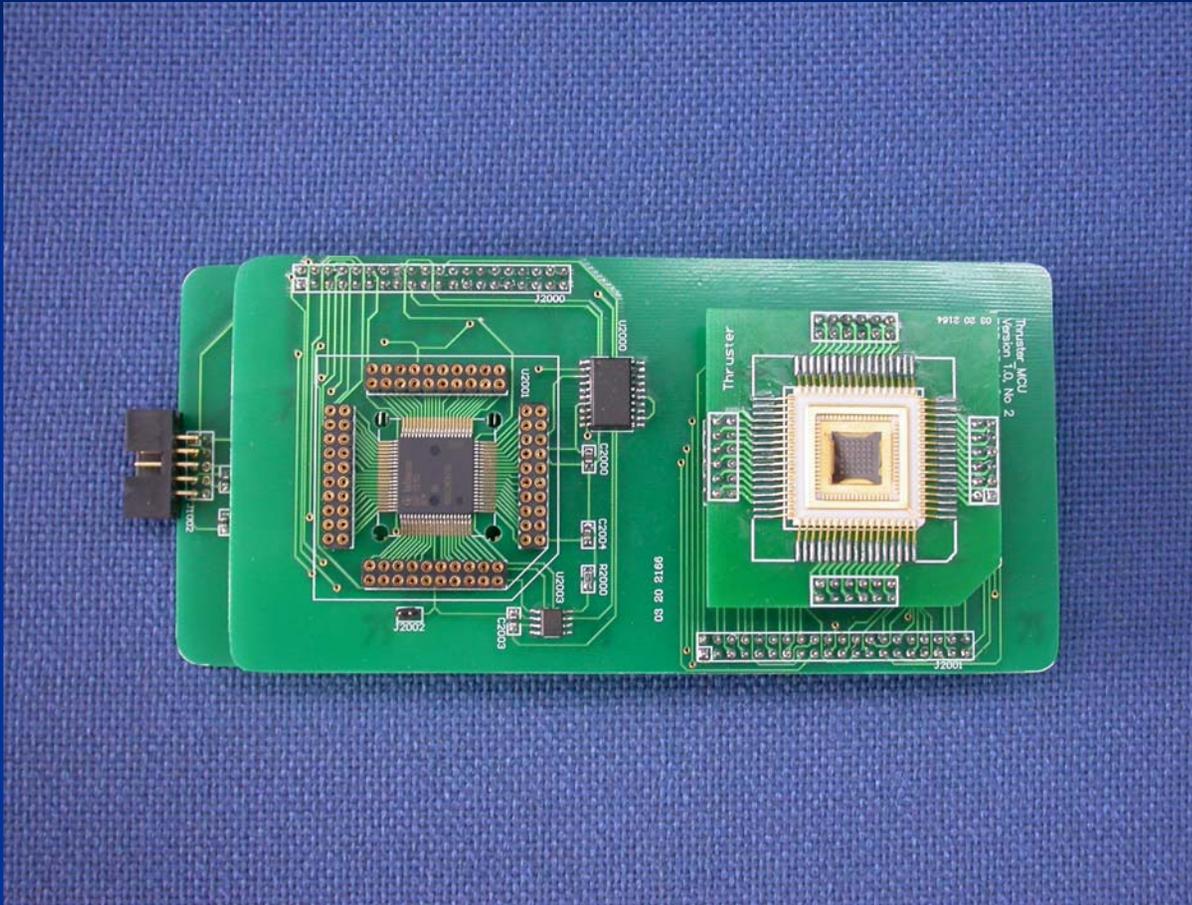
SEM of KOH Wet Etching Chamber with Four Exhaust Holes, Bond Pads, Ignitors

# MICROPROPULSION

## Assembled Thruster Prototype



## Micro Propulsion Subsystem Module



Command from OBC transmit to the micro-propulsion module through the RS232 or CAN bus.

## Design and Fabrication Issues Discussion

- **Nozzle array**
  - Quasi-laval binary geometry
  - No diaphragm, eliminate the energy expense with rupture
  - How to ensure the adequate pressure? Nozzle geometry? Suitable ratio of  $A_t$  to  $A_c$
  - Next Stage: Thermal isolation - Surface thermal oxide layer
- **Chamber**
  - With exhaust holes around, hope to improve the combustion performance
  - Next Stage:
    - Adiabatic film, coating thermal oxide
    - Reduce Volume, increase arrays
- **Ignitor array**
  - Now: Pt resistor on the Prex7740, oxidation resistance, but low density of integration
  - Next Stage: Addressing and driving circuit on the SOI wafer, cavity on the back side for thermal isolation
- **Bonding Approach**
  - Bottom layer and middle layer: anodic bonding before propellant filled
  - Top layer: glue in the less of  $100^\circ\text{C}$  after propellant filled
  - Next Stage: Si – Au (or Al) - Si Bonding, not require any glue

## Principle of The Propellant Choice

- Low energy threshold for igniting: require lead styphnate
- Withstand high transient pressure for bonding
- Solid propellant, easy storage
- No leaking
- Fluidity in certain condition, easy to cast

## A-Type Propellant Performance Specification

### ■ A-type Propellant: HTPB/AP

Item	Value	
Characteristic Rate C (m/s)	1379.4	
Flame Temperature $T_e$ (K)	2046	
Density (g/cm <sup>3</sup> )	1.625	
Specific Heat $C_p$	1.5	
Combustion Rate (mm/s)	Pre exponential factor a	5.52
	Exponential coefficient n	0.45
Thermal Capacity ratio $\gamma$	1.25	
Mean Molecular Weight $M_g$ (g/mol)	21.08	
Mole $N_g$ (mol/Kg)	47.43	

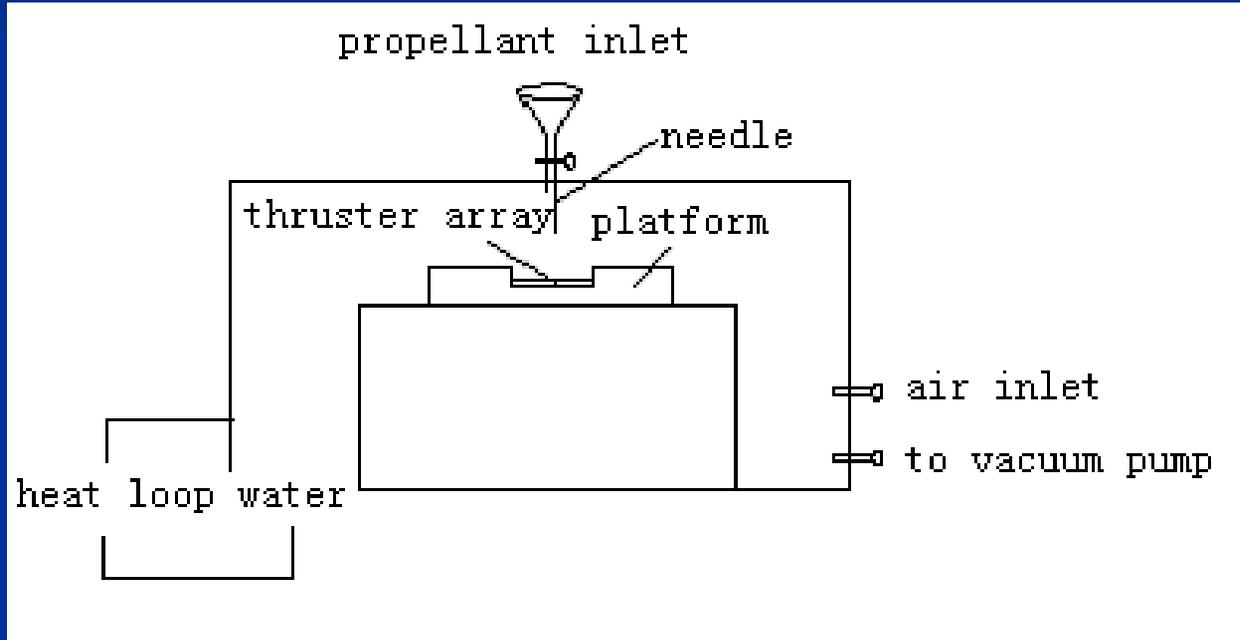
## B-Type Propellant Performance Specification

- B-type Propellant: HTPB/AP/Mg

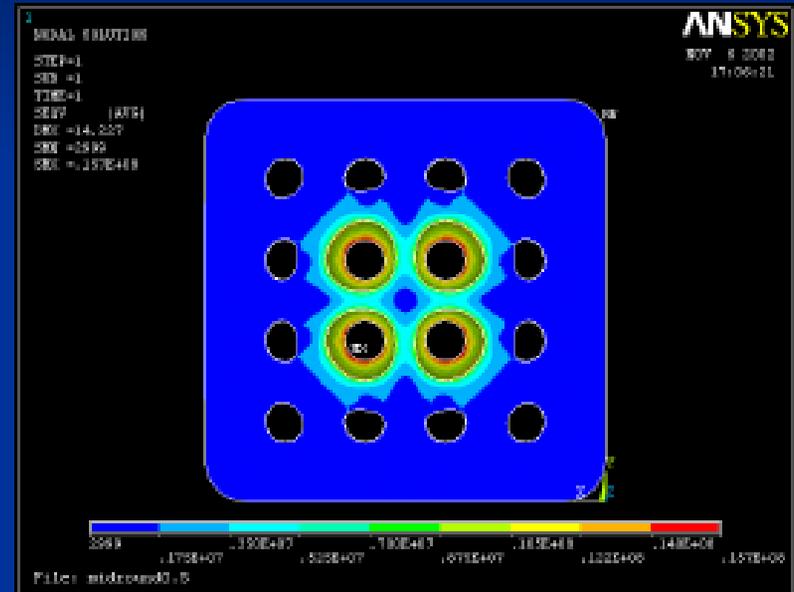
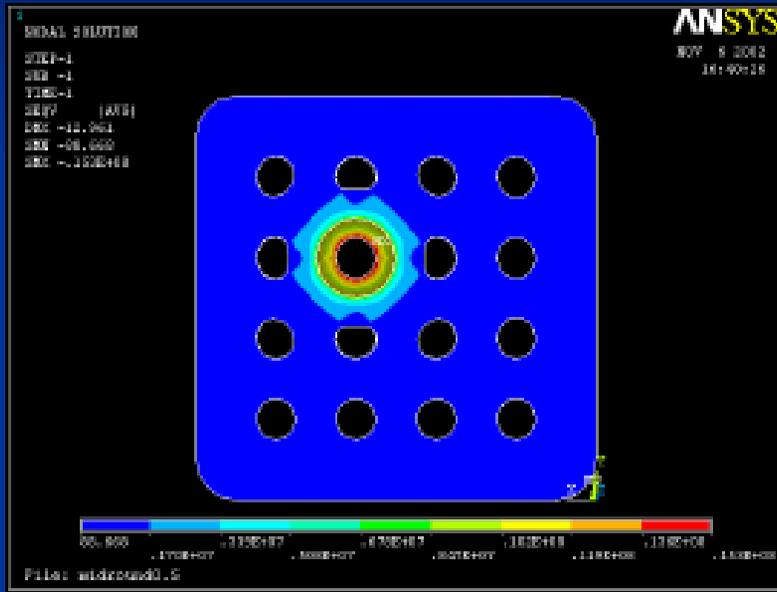
Item	Value	
Characteristic Rate C (m/s)	1427.4	
Flame Temperature T <sub>c</sub> (K)	2223	
Density (g/cm <sup>3</sup> )	1.614	
Specific Heat C <sub>p</sub>	1.53	
Combustion Rate (mm/s)	Pre exponential factor a	5.63
	Exponential coefficient n	0.45
Thermal Capacity ratio $\gamma$	1.25	
Mean Molecular Weight M <sub>g</sub> (g/mol)	19.51	
Mole N <sub>g</sub> (mol/Kg)	47.54	

# MICROPROPULSION

## Schematic of the System to Fill Chamber with Propellant



## Stress Distribution at Different Operating Mode



500  $\mu$  m diameter chamber VonMises stress distribution under single unit firing and four neighbour units firing

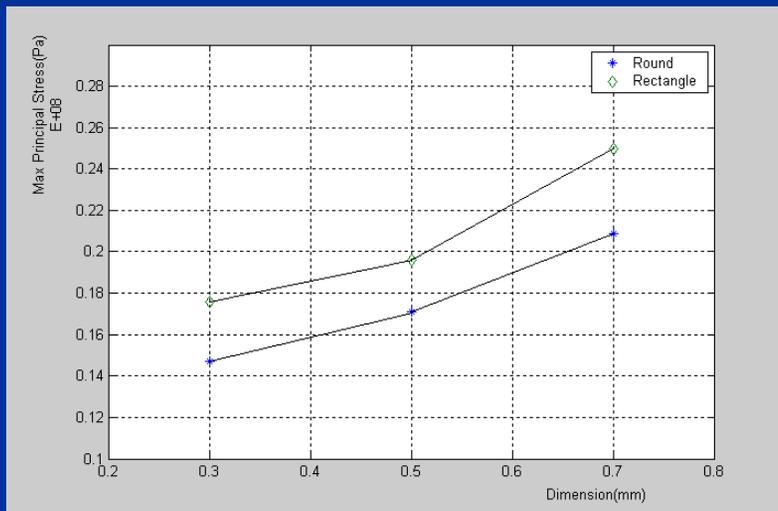
## Ultimate Stress and Strain List

- Maximal stress and strain under different working pressure

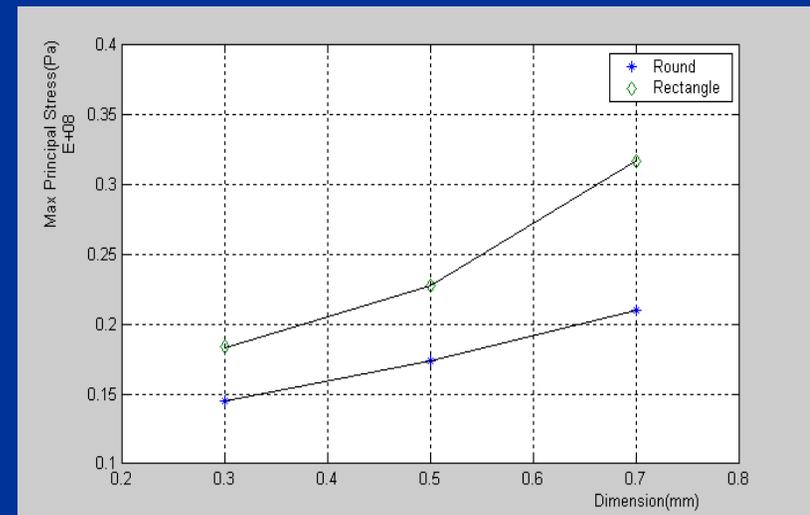
Pressure Result	Type	0.7 (MPa)	2 (MPa)	5 (MPa)	10 (MPa)	20 (MPa)
VonMises (Pa) MAX (Absolute Value)	Single	0.12632E+ 07	0.36091E+ 07	0.90228E+ 07	0.18046E+ 08	0.36091E+ 08
	Four	0.13379E+ 07	0.38225E+ 07	0.95561E+ 07	0.19112E+ 08	0.38225E+ 08
Strain ( $\mu\text{m}$ ) MAX (Absolute Value)	Single	2.1133	6.0380	15.095	30.190	60.380
	Four	2.4485	6.9956	17.489	34.978	69.956

## Graph of Relation between Ultimate Stress and Chamber Diameter

- Utmost Stress Relative to Chamber Diameter



Single Chamber Working State



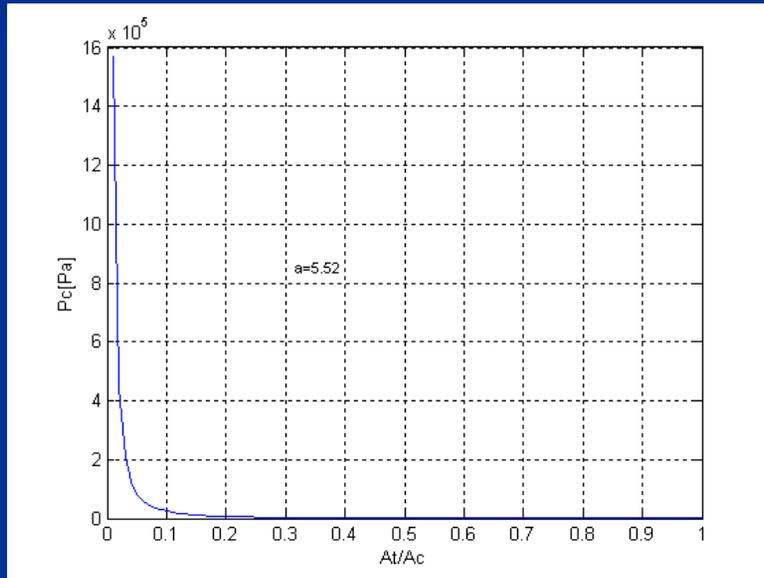
Four Chambers Working State

## Thrusts Performance Prediction

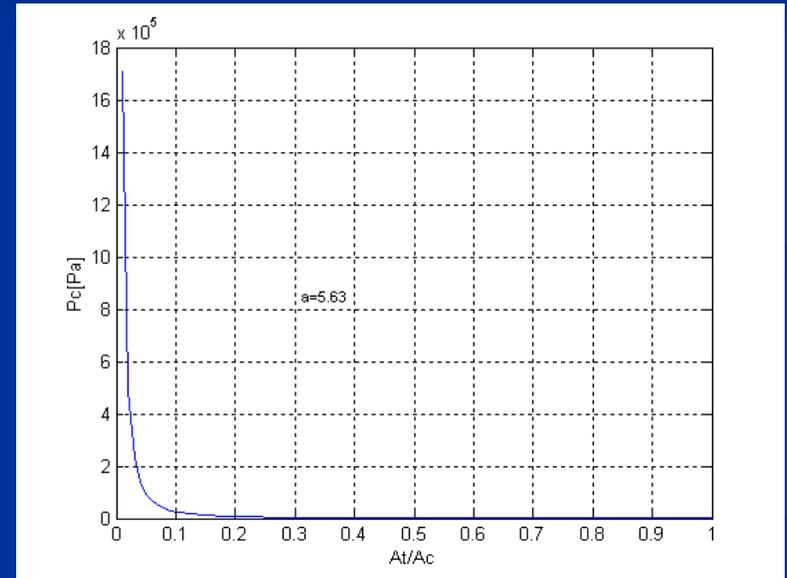
- **Basic thermodynamic principles are used, taking the following considerations**
  - The propellant chemical reaction products are homogeneous.
  - All the species of the working fluid are gaseous.
  - The combustion gases follow the ideal gas law.
  - The propellant flow is steady and constant.
  - The chamber and nozzle wall is adiabatic.
  - The nozzle is Laval geometry.
  - The gases velocity, pressure, temperature and density are uniform across the section.
  - Boundary layer effects are neglected.
  - There is no shock waves and discontinuities in the nozzle flow.

## Chamber Pressure Calculation

- Functional relation between pressure  $P_c$  in the chamber and the throat-to-chamber section ratio  $A_t/A_c$



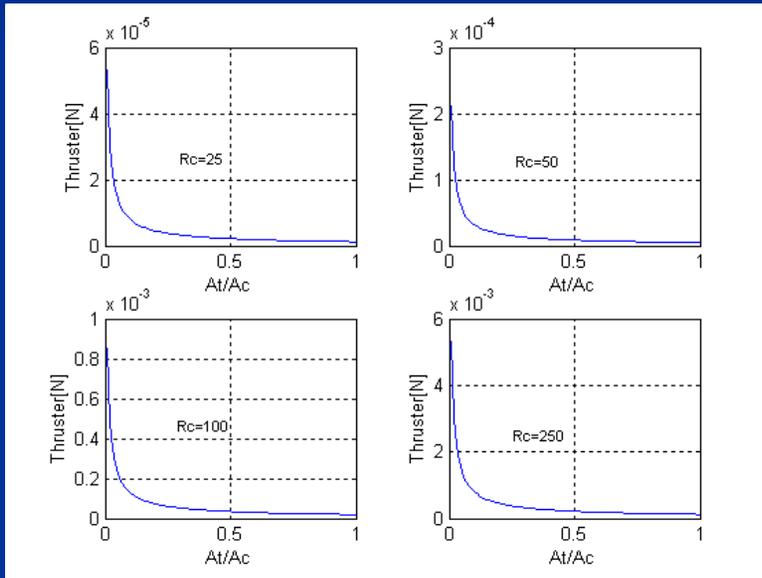
A-type propellant



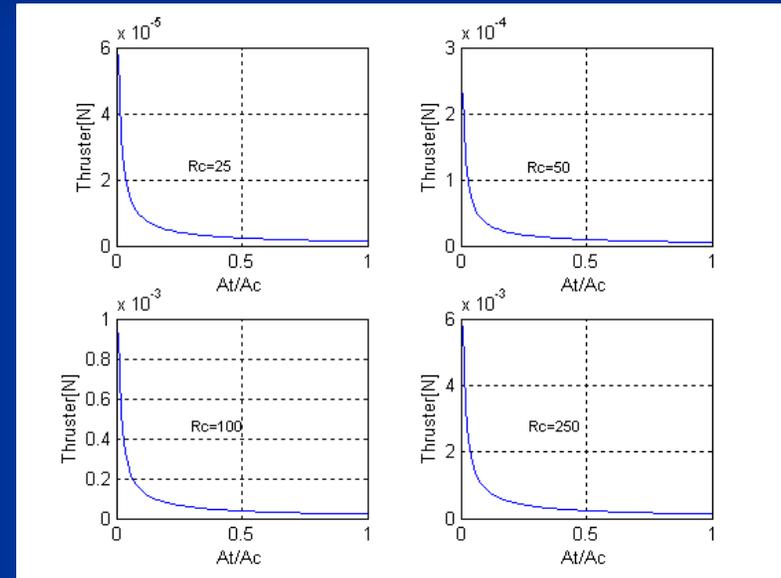
B-type propellant

## Thrusts Performance Calculation

- Functional relation between thruster  $F$  in the chamber and the throat-to-chamber section ratio  $A_t/A_c$



A-type propellant

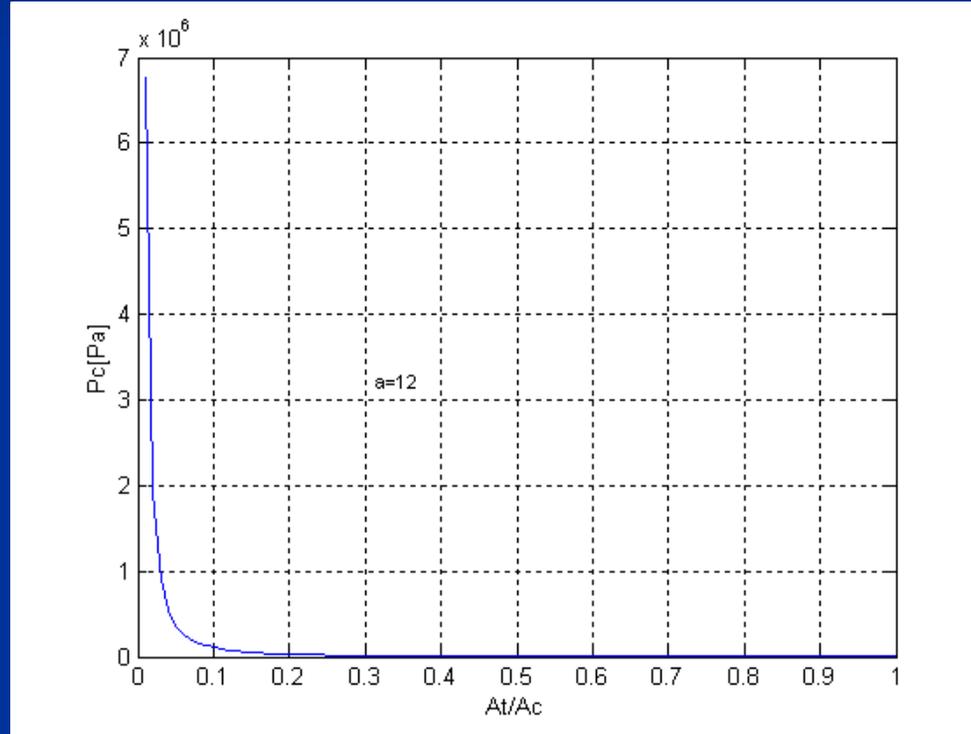


B-type propellant

# MICROPROPULSION

## Chamber Pressure Calculation with Increasing Combustion Rate

- Increasing the pre exponential factor  $a$  and the ratio  $A_c/A_t$  help to increase the pressure  $P_c$



## Conclusion

- MEMS solid propellant propulsion is a better option.
- Real thrust force and special impulse is lower than the theoretical value.
- Increasing the combustion rate and the throat-to-chamber section ratio is a efficient way to enlarge the thrust force.
- Increasing the combustion rate will improve the thruster firing performance, and ensure the combustion sufficiently.
- In order to increase the special impulse, thermal isolation of chamber and nozzle must be adopt.
- Under the micro scale condition, the boundary layer effect, thermal transfer and the propellant combustion mechanics need be further studied on.

## Team Members Address

### ■ Design and Fabrication

Prof. YOU Zheng  
ZHANG Gaofei

[yz-dpi@mail.tsinghua.edu.cn](mailto:yz-dpi@mail.tsinghua.edu.cn)  
[zhanggf@post.pim.tsinghua.edu.cn](mailto:zhanggf@post.pim.tsinghua.edu.cn)

Dr. REN Dahai

[rendh@ntl.pim.tsinghua.edu.cn](mailto:rendh@ntl.pim.tsinghua.edu.cn)

### ■ Propellant Research

Dr. Hu Songqi

[pine\\_hu@263.net](mailto:pine_hu@263.net)

Department of Precision Instruments & Mechanology, Tsinghua University,  
Beijing 100084, P.R. China

TEL: (8610)62776000 FAX: (8610)62782308

**Thank You!**

*Any Comments or Suggestions  
Will be Highly Appreciated!*